

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : THE COMMISSIONER IS AUTHORIZED
Shoriki NARITA et al. : TO CHARGE ANY DEFICIENCY IN THE
Serial No. NEW : FEES FOR THIS PAPER TO DEPOSIT
Filed August 29, 2003 : ACCOUNT NO. 23-0975
: Attn: APPLICATION BRANCH
: Attorney Docket No. 2003_1226

BUMP FORMING APPARATUS FOR
CHARGE APPEARANCE SEMICONDUCTOR
SUBSTRATE, CHARGE REMOVAL METHOD
FOR CHARGE APPEARANCE SEMICONDUCTOR
SUBSTRATE, CHARGE REMOVING UNIT FOR
CHARGE APPEARANCE SEMICONDUCTOR
SUBSTRATE, AND CHARGE APPEARANCE
SEMICONDUCTOR SUBSTRATE
(Rule 1.53(b) Divisional
of Serial No. 10/019,700,
Filed January 2, 2002)

CLAIM OF PRIORITY UNDER 35 USC 119

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450


Sir:

Applicants in the above-entitled application hereby claim the date of priority under the International Convention of Japanese Patent Application No. 11-189053, filed July 2, 1999, Japanese Patent Application No. 11-293702, filed October 15, 1999, Japanese Patent Application No. 11-308855, filed October 29, 1999, Japanese Patent Application No. 11-323979, filed November 15, 1999 and Japanese Patent Application No. 2000-184467, filed June 20, 2000, as acknowledged in the Declaration of this application.

The priority documents were received by the International Bureau on August 18, 2000. A copy of the Form PCT/IB/304 is of record in parent application No. 10/019,700.

Respectfully submitted,

Shoriki NARITA et al.

By 

Michael S. Huppert
Registration No. 40,268
Attorney for Applicants

MSH/kjf
Washington, D.C. 20006-1021
Telephone (202) 721-8200
Facsimile (202) 721-8250
August 29, 2003